

U.S. Department of Commerce, Patent and Trademark Office LIST OF RELEVANT ART CITED BY APPLICANT (Use several sheets if necessary)				Docket No.: 8201/Y01/SYNX/JW		Serial No.: 10/764,620	
<div style="position: relative; height: 100px;"> <div style="position: absolute; top: 0; left: 0; width: 100%; height: 100%; border: 1px solid black; border-radius: 50%; text-align: center; color: black; font-weight: bold; line-height: 1;"> OIPE NOV 07 2005 IAP29 U.S. PATENT & TRADEMARK OFFICE </div> </div>				Applicants: Michael R. Rice, et al			
				Filing Date: January 26, 2004		Group: 2125	
U.S. Patent Documents							
*Examiner Initial	Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate	
CK	US-1	5,544,350	08/06/96	Hung et al.			
CK	US-2	5,612,886	03/18/97	Yi-Cherng Weng			
CK	US-3	5,818,716	10/06/98	Chin et al.			
CK	US-4	5,825,650	10/20/98	Tza-Huei Wang			
CK	US-5	5,971,585	10/26/99	Dangat et al.			
CK	US-6	6,128,588	10/03/00	Guillermo Rudolfo Chacon			
CK	US-7	6,196,001	03/06/01	Tannous et al.			
CK	US-8	6,415,260	07/02/02	Yang et al.			
	US-9						
	US-10						
	US-11						
Foreign Patent Documents							
		Document Number	Date	Country	Class	Subclass	Translation Yes No
CK	F-1	JP 55091839 A	07/11/80	Japan			Abstract
CK	F-2	JP 58028860 A	02/19/83	Japan			Abstract
CK	F-3	JP 60049623 A	03/18/85	Japan			Abstract
CK	F-4	JP 01181156 A	07/19/89	Japan			Abstract
CK	F-5	JP 01257549 A	10/13/89	Japan			Abstract
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
CK	OT-1	Przewlocki, H. et al., "DIASTEMOS-computerized system of IC manufacturing control and diagnostics", 1990, Elektronika, Vol. 31 No. 11-12, Pgs. 38-40, Polish Language. (Abstract only)					
CK	OT-2	Lovell, A. M. et al., "Cell automation: integrating manufacturing with robotics", Dec. 1990, Solid State Technology, Vol. 33 No. 12, Pg. 37-9.					
CK	OT-3	Prasad, K., "A generic computer simulation model to characterize photolithography manufacturing area in an IC FAB facility", Sept. 1991, IEEE Transactions on Components, Hybrids, and Manufacturing Technology, Vol. 14 No. 3, Pg. 483-7.					
Examiner: <i>Charles Koyne</i>		Date Considered: <i>12/9/05</i>					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.							

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	US-12						
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Foreign Patent Documents							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
CK	F-6	JP 02015647 A	01/19/90	Japan			Abstract	
CK	F-7	JP 05128131 A	05/25/93	Japan			Abstract	
CK	F-8	JP 05290053 A	11/05/93	Japan			Abstract	
CK	F-9	JP 06260545 A	09/16/94	Japan			Abstract	
CK	F-10	JP 08249044 A	09/27/96	Japan			Abstract	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
CK	OT-4	Ehteshami, B. et al., "Trade-offs in cycle time management: hot lots", May 1992, IEEE Transactions on Semiconductor Manufacturing, Vol. 5 No. 2, Pg. 101-6.
CK	OT-5	Lou, S. et al., "Using simulation to test the robustness of various existing production control policies", 1991, 1991 Winter Simulation Conference Proceedings, IEEE, Pg. 261-9.
CK	OT-6	Berg, R. et al., "The formula: world class manufacturing for hybrid thin-film component production", 1992, IEEE/SEMI International Semiconductor Manufacturing Science Symposium, Pgs. 53-60.

Examiner <i>Chin Kiang</i>	Date Considered 12/9/01
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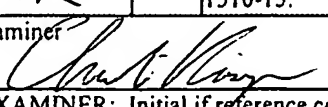
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	US-23						
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Foreign Patent Documents							Translation	
	Document Number	Date	Country	Class	Subclass	Yes	No	
CK	F-11 JP 09115817 A	05/02/97	Japan			Abstract		
CK	F-12 JP 10135096 A	05/22/98	Japan			Abstract		
CK	F-13 JP 11176717 A	07/02/99	Japan			Abstract		
CK	F-14 JP 11296208 A	10/29/99	Japan			Abstract		
CK	F-15 JP 01332464 A	11/30/01	Japan			Abstract		

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
CK	OT-7	Naguib, H., "The implementation of total quality management in a semiconductor manufacturing operation", 1992, IEEE/SEMI International Semiconductor Manufacturing Science Symposium, Pg. 63-7.
CK	OT-8	Rose, D., "Productivity enhancement", 1992, IEEE/SEMI International Semiconductor Manufacturing Science Symposium, Pg. 68.
CK	OT-9	Narayanan, S. et al., "Object-oriented simulation to support operator decision making in semiconductor manufacturing", 1992, 1992 IEEE International Conference on Systems, Man and Cybernetics, Vol. 2, Pg 1510-15.

Examiner 	Date Considered 12/9/05
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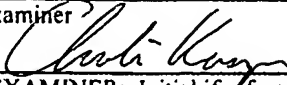
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Foreign Patent Documents							Translation	
	Document Number	Date	Country	Class	Subclass	Yes	No	
CK	F-16 JP 03007584 A	01/10/03	Japan			Abstract		
CK	F-17 DE 19715974 A1	10/22/98	Germany			Abstract		
CK	F-18 EP 1128246 A2	08/29/01	EPO			X		
	F-19							
	F-20							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)	
CK	OT-10 Leonovich, G. A. et al., "Integrated cost and productivity learning in CMOS semiconductor manufacturing", Jan.-March 1995, IBM Journal of Research and Development, Vol. 39 No. 1-2, Pg. 201-13.
CK	OT-11 Leonovich, G., "An approach for optimizing WIP/cycle time/output in a semiconductor fabricator", 1994, Sixteenth IEEE/CPMT International Electronics Manufacturing Technology Symposium. 'Low-Cost Manufacturing Technologies for Tomorrow's Global Economy'. Proceedings 1994 IEMT Symposium, Vol. 1, Pg. 108-11.
CK	OT-12 Schomig, A. K. et al., "Performance modelling of pull manufacturing systems with batch servers", 1995, Proceedings 1995 INRIA/IEEE Symposium on Emerging Technologies and Factory Automation. ETFA '95, Vol. 3, Pg. 175-83.

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U.S. Patent Documents

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	US-45					
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- Foreign Patent Documents

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	Document Number	Date	Country	Class	Subclass	Yes	No
	F-21						
	F-22						
	F-23						
	F-24						
	F-25						

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

OK	OT-13	Juba, R. C. et al., "Production improvements using a forward scheduler", 1996, Seventeenth IEEE/CPMT International Electronics Manufacturing Technology Symposium 'Manufacturing Technologies - Present and Future', Pg. 205-9.
CR	OT-14	Fuller, L. F. et al., "Improving manufacturing performance at the Rochester Institute of Technology integrated circuit factory", 1995, IEEE/SEMI 1995 Advanced Semiconductor Manufacturing Conference and Workshop. Theme - Semiconductor Manufacturing: Economic Solutions for the 21st Century. ASMC '95 Proceedings, Pg. 350-5.
OK	OT-15	Houmin, Yan et al., "Testing the robustness of two-boundary control policies in semiconductor manufacturing", May 1996, IEEE Transactions on Semiconductor Manufacturing, Vol. 9, No. 2, Pg. 285-8.

Examiner <i>Chad King</i>	Date Considered 12/9/05
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	US-56						
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Foreign Patent Documents

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	F-26							
	F-27							
	F-28							
	F-29							
	F-30							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

CK	OT-16	Lopez, M. J. et al., "Performance models of systems of multiple cluster tools", 1996, Nineteenth IEEE/CPMT International Electronics Manufacturing Technology Symposium. Proceedings 1996 IEMT Symposium, Pgs. 57-65.
CK	OT-17	Collins, D. W. et al., "Implementation of Minimum Inventory Variability Scheduling 1-Step Ahead Policy(R) in a large semiconductor manufacturing facility", 1997, 1997 IEEE 6th International Conference on Emerging Technologies and Factory Automation Proceedings, Pgs. 497-504.
CK	OT-18	Labanowski, L., "Improving overall fabricator performance using the continuous improvement methodology", 1997, 1997 IEEE/SEMI Advanced Semiconductor Manufacturing Conference and Workshop. Theme - The Quest for Semiconductor Manufacturing Excellence: Leading the Charge into the 21st Century. ASMC Proceedings, Pg. 405-9.

Examiner: <i>Charli Kung</i>	Date Considered: <i>12/9/05</i>
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	US-78						
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Foreign Patent Documents							Translation	
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	F-36							
	F-37							
	F-38							
	F-39							
	F-40							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
CR	OT-22	Rose, O., " WIP evolution of a semiconductor factory after a bottleneck workcenter breakdown", 1998, 1998 Winter Simulation Conference. Proceedings, Vol. 2, Pgs. 997-1003.
CK	OT-23	Iriuchijima, K. et al., "WIP allocation planning for semiconductor factories", 1998, Proceedings of the 37th IEEE Conference on Decision and Control, Vol. 3, Pg. 2716-21.
CK	OT-24	Weiss, M., "New twists on 300 mm fab design and layout", July 1999, Semiconductor International, Vol. 22 No. 8, Pgs. 103-4, 106, 108.


Examiner <i>Charlie Wang</i>	Date Considered 12/9/05
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	US-67						
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Foreign Patent Documents							Translation	
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	F-31							
	F-32							
	F-33							
	F-34							
	F-35							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
CK	OT-19	Dudde, R. et al., "Flexible data registration and automation in semiconductor production", 1997, Proceedings of the SPIE - The International Society for Optical Engineering, Pg. 171-81.
CK	OT-20	Padillo, J. M. et al., "A strategic domain: IE in the semiconductor industry", March 1998, IIE Solutions, Pgs. 36-40, 42.
CK	OT-21	Collins, D. W. et al., "Investigation of minimum inventory variability scheduling policies in a large semiconductor manufacturing facility", 1997, Proceedings of the 1997 American Control Conference, Vol. 3, Pg. 1924-8.

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	US-89						
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Foreign Patent Documents							Translation	
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	F-41							
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	F-44							
	F-45							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)	
<i>CR</i>	OT-25 Van Antwerp, K. et al., "Improving work-in-progress visibility with active product tags YASIC manufacture", Oct. 1999, Micro, Vol. 17 No. 9, Pgs. 67-9, 72-3.
<i>CK</i>	OT-26 Martin, D. P., "Total operational efficiency (TOE): the determination of two capacity and cycle time components and their relationship to productivity improvements in a semiconductor manufacturing line", 1999, 10th Annual IEEE/SEMI. Advanced Semiconductor Manufacturing Conference and Workshop. ASMC 99 Proceedings, Pgs. 37-41.
<i>CK</i>	OT-27 Martin, D. P., "Capacity and cycle time-throughput understanding system (CAC-TUS) an analysis tool to determine the components of capacity and cycle time in a semiconductor manufacturing line", 1999, 10th Annual IEEE/SEMI. Advanced Semiconductor Manufacturing Conference and Workshop. ASMC 99 Proceedings, Pg. 127-31.

Examiner <i>Christi Kray</i>	Date Considered <i>12/9/05</i>
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	US-100						
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	F-46							
	F-47							
	F-48							
	F-49							
	F-50							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
CK	OT-28	Marcoux, P. et al., "Determining capacity loss from operational and technical deployment practices in a semiconductor manufacturing line", 1999, 1999 IEEE International Symposium on Semiconductor Manufacturing Conference Proceedings, Pg. 3-5.
CK	OT-29	Chen, J. C. et al., "Capacity planning for a twin fab", 1999, 1999 IEEE International Symposium on Semiconductor Manufacturing Conference Proceedings, Pg. 317-20.
CK	OT-30	Wei Jun-Hu et al., "Optimization methodology in simulation-based scheduling for semiconductor manufacturing", Oct. 2000, Information and Control, Vol. 29 No. 5, Pg. 425-30, Chinese language. (Abstract only)

Examiner: <i>Charles King</i>	Date Considered: <i>12/9/05</i>
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	F-51							
	F-52							
	F-53							
	F-54							
	F-55							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
CK	OT-31	Hughlett, E., "Incremental levels of automation in the compound semiconductor fab", Aug. 2001, Compound Semiconductor, Vol. 7 No. 7, Pg. 69-73.
CK	OT-32	Sarin, S. C. et al., "Reduction of average cycle time at a wafer fabrication facility", 2001, 2001 GaAs MANTECH Conference. Digest of Papers, Pg. 241-6.
CK	OT-33	Saito, K. et al., "A simulation study on periodical priority dispatching of WIP for product-mix fabrication", 2002, 13th Annual IEEE/SEMI Advanced Semiconductor Manufacturing Conference. Advancing the Science and Technology of Semiconductor Manufacturing. ASMC 2002, Pg. 33-7.

Examiner: <i>Charlie Kray</i>	Date Considered: <i>Rice 12/9/05</i>
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	F-57							
	F-58							
	F-59							
	F-60							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
CK	OT-34	Wang, J. et al., "The improvement of automated material handling system traffic control", 2002, 2002 Semiconductor Manufacturing Technology Workshop, Pg. 271-4.
CK	OT-35	Wei Jie Lee, "Optimize WIP scale through simulation approach with WIP, turn-over rate and cycle time regression analysis in semiconductor fabrication", 2002, 2002 Semiconductor Manufacturing Technology Workshop, Pg. 299-301.
CK	OT-36	Young Hoon Lee et al., "Push-pull production planning of the re-entrant process", 2003, International Journal of Advanced Manufacturing Technology, Vol. 22 No. 11-12, Pg. 922-31.

Examiner: <i>Charles Henry</i>	Date Considered: <i>12/9/05</i>
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	F-61							
	F-62							
	F-63							
	F-64							
	F-65							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
CK	OT-37	Garlid, Scott C., "From philosophy to reality. Interpreting the rules of JIT for IC manufacturing", 1989, SME Technical Paper (Series) MS. Publ by SME, Pg. 797.
CK	OT-38	Anon, " Wafer level automation", Jan. 1995, European Semiconductor, Vol. 17 No. 1, Pg. 2.
CK	OT-39	Anon, "Coming of fab-wide automation", May 1998, European Semiconductor Design Production Assembly, Vol. 20 No. 5, Pg. 21-22.

Examiner: <i>Chad Hargis</i>	Date Considered: <i>12/9/05</i>
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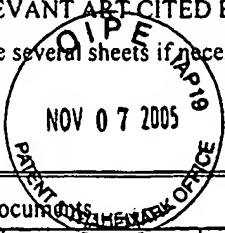
U.S. Patent Documents							
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	US-144						
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	US-147						
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	US-154						

Foreign Patent Documents							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	F-66							
	F-67							
	F-68							
	F-69							
	F-70							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
CK	OT-40	Pierce, Neal G. et al., " Dynamic dispatch and graphical monitoring system", 1999, IEEE International Symposium on Semiconductor Manufacturing Conference, Proceedings 1999, Pg. 65-68.
CK	OT-41	Nagesh, Sukhi et al., " Intelligent second-generation MES solutions for 300mm fabs", 2000, Solid State Technology, Vol. 43 No. 6, Pgs. 133-134, 136, 138.
	OT-42	

Examiner <i>Charles Kasper</i>	Date Considered 12/9/05
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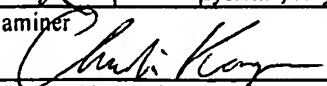
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U.S. Department of Commerce, Patent and Trademark Office LIST OF RELEVANT ART CITED BY APPLICANT (Use several sheets if necessary)				Docket No.: 8201/Y01/SYNX/JW		Serial No.: 10/764,620	
				Applicants: Michael R. Rice, et al			
				Filing Date: January 26, 2004		Group: 2125	

U.S. Patent Documents							
*Examiner Initial	Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate	
CK	US-1	5,256,204	10/26/93 Hong J. Wu				
CK	US-2	5,668,056	09/16/97 Wu et al.				
CK	US-3	5,976,199	11/02/99 Wu et al.				
	US-4						
	US-5						
	US-6						
	US-7						
	US-8						
	US-9						
	US-10						
	US-11						

Foreign Patent Documents							Translation	
	Document Number	Date	Country	Class	Subclass	Yes	No	
CK	F-1 JP 2000012646 A2	01/14/00	Japan			Abstract Only		
	F-2							
	F-3							
	F-4							
	F-5							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
CK	OT-1	"300mm single-wafer transport", July 1999, Solid State Technology - semiconductor manufacturing and wafer fabrication, Semicon West '99 Product Spotlight, pg. 5.
CK	OT-2	"300mm single-wafer handling", April 2000, Solid State Technology, Product News, <www.solid-state.com>, pg. 99.
CK	OT-3	Griessing, Juergen et al., "Assessing the feasibility of a 300-mm test and monitor wafer handling and logistics system", July 2000, Micro: The 300-mm Imperative, pgs. 1-19.

Examiner 	Date Considered 12/9/05
---	----------------------------

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U.S. Department of Commerce, Patent and Trademark Office LIST OF RELEVANT ART CITED BY APPLICANT (Use several sheets if necessary)	Docket No.: 8201/Y01/SYNX/JW	Serial No.: 10/764,620
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U.S. Patent Documents

*Examiner Initial		Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate
	US-12						
	US-13						
	US-14						
	US-15						
	US-16						
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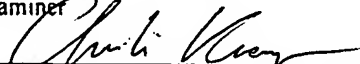
Foreign Patent Documents

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	F-6							
	F-7							
	F-8							
	F-9							
	F-10							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

CK	OT-4	"The Leading Company in Micro environment", January 3, 2002, Incam Solutions Company, pgs. 1-2.
CK	OT-5	"Improved wafer isolation and additional flexibility", January 3, 2002, Incam Solutions Company SWIF technology, pgs. 1-2.
CK	OT-6	"SEMI standards compliance" and "Related SEMI standards", January 3, 2002, Incam Solutions Related standards, pg. 1.

Examiner 	Date Considered 12/9/05
---	----------------------------

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U.S. Department of Commerce, Patent and Trademark Office LIST OF RELEVANT ART CITED BY APPLICANT (Use several sheets if necessary)				Docket No.: 8201/Y01/SYNX/JW		Serial No.: 10/764,620	
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U.S. Patent Documents							
*Examiner Initial	Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate	
	US-23						
	US-24						
	US-25						
	US-26						
	US-27						
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	US-31						
	US-32						
	US-33						

Foreign Patent Documents							Translation	
Document Number	Date	Country	Class	Subclass	Yes	No		
F-11								
F-12								
F-13								
F-14								
F-15								

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)	
CK	OT-7 "Single Wafer Lots Solution", January 3, 2002, Incam Solutions References, pg. 1.
OT-8	
OT-9	

Examiner <i>Charles Kerry</i>	Date Considered <i>12/9/05</i>
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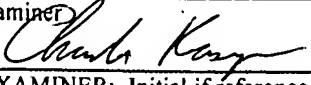
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U.S. Department of Commerce, Patent and Trademark Office <div style="display: flex; align-items: center;"> <div style="border: 1px solid black; border-radius: 50%; padding: 10px; text-align: center; margin-right: 10px;"> OIPE AUG 31 2005 PATENT & TRADEMARK OFFICE </div> <div> LIST OF RELEVANT ART CITED BY APPLICANT (Use several sheets if necessary) </div> </div>				Docket No.: 8201/Y01/SYNX/JW		Serial No.: 10/764,620	
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U.S. Patent Documents							
*Examiner Initial	Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate	
CK	US-1	5,110,249	05/05/92	Arthur E. Norman			
CK	US-2	6,036,426	03/14/00	Gary Hillman			
CK	US-3	6,183,186	02/06/01	Peltola et al.			
	US-4						
	US-5						
	US-6						
	US-7						
	US-8						
	US-9						
	US-10						
	US-11						

Foreign Patent Documents							Translation	
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CK F-1 EP 0 277 536 A	08/10/88	EPO			X (Abstract)			
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F-4								
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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)	
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OT-2	
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Examiner: 	Date Considered: 12/9/05
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				Filing Date: January 26, 2004		Group: 2125	

U.S. Patent Documents							
*Examiner Initial		Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate
CK	US-1	4,401,522	08/30/83	Buschow et al.			
CK	US-2	4,534,843	08/13/85	Hirbour et al.			
CK	US-3	4,540,088	09/10/85	Bergh			
CK	US-4	4,650,264	03/17/87	Dahnert			
CK	US-5	4,775,046	10/04/88	Gramarossa et al.			
CK	US-6	6,235,634	05/22/01	Law et al.			
CK	US-7	2002/0090282	07/11/02	Bachrach			
CK	US-8	2003/0010449	01/16/03	Gramarossa et al.			
	US-9						
	US-10						
	US-11						

Foreign Patent Documents							Translation	
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	F-1							
	F-2							
	F-3							
	F-4							
	F-5							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)	
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Examiner: <i>Charles Kay</i>	Date Considered: 12/9/05
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